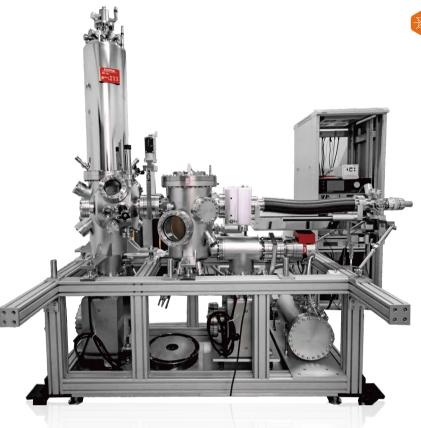
UHV-LT-SPM-MBE SYSTEM







New Pan-type scanner with q-Plus AFM function, modular design, easy to maintain

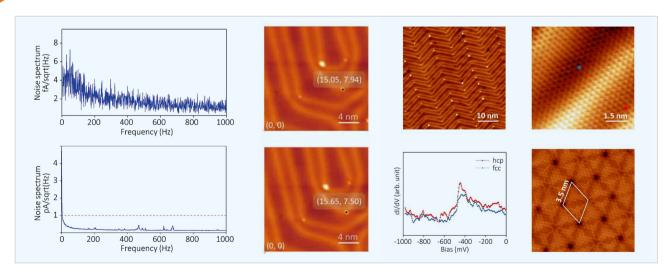
Optional optical access, suitable for optical experiment

Multi-sources MBE sample preparation, in-situ deposition

Compact Load-Lock chamber, fast sample transfer



STM TEST DATA



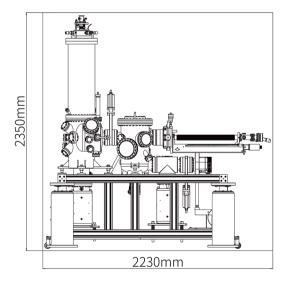
A detailed introduction of the system was successfully published in AIP Review of Scientific Instruments 89, 113705 (2018); doi: 10.1063/1.5046466 Article link: Https://aip.scitation.org/doi/10.1063/1.5046466



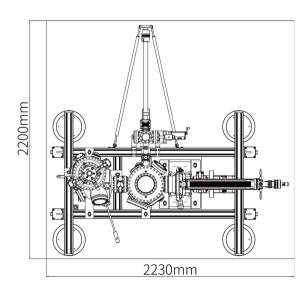


III TECHNICAL DATA

| Scanner | Optical compatible | |
|--------------------------|---|--|
| | Modular design with q-Plus AFM Function | |
| | Lowest operational temperature | ≤5K |
| | X/Y/Z Coarse range | 2×2×8mm |
| | X/Y/Z Scan range | 6×6×2μm @ RT |
| | | 1.5×1.5×0.5μm@ LHe |
| | LHe holding time | ≥50h (Cryostat bath capacity: 4L LHe, 15L LN2) |
| | Temperature stability | <0.2nm/h |
| | Resolution | Atomic resolution |
| Manipulator | X/Y Axis | ± 12.5 mm manually actuated |
| | Z Axis | 450mm stepper motorized |
| | Primary (polar) rotation | $\pm 180^\circ$ manually actuated |
| | Secondary (azimuthal) rotation | $\pm 180^\circ$ manually actuated |
| | Temperature range | 120K~RT (LN2 cooling) |
| | | RT~1450K (E-Beam heating) |
| Evaporators (up to 6) | DN40CF (O.D. 2.75") | Qty: 5 |
| | DN63CF (O.D. 4.5'') | Qty: 1 |
| Options | Optical access, suitable for optical experiment | |
| | RHEED | |
| | LEED | |
| | Ion Gun (3KeV/5KeV) | |
| | | |







Top view

